## What is claimed is:

- A gas plasma emission source comprising:
   a resonant cavity; and
   a solid state power source coupled to the resonant cavity.
- 2. The emission source of claim 1, further including a cable coupled between the solid state power source and the resonant cavity.
- 3. The emission source of claim 1, wherein the resonant cavity includes a tube disposed through the resonant cavity.
  - 4. The emission source of claim 1, wherein:

the solid state power source couples into the resonant cavity sufficient power to sustain a plasma in a gas disposed within the resonant cavity, the sufficient power being less than 300 watts;

the plasma constitutes a fluctuating load on the solid state power source; and the sufficient power is substantially stable with respect to the fluctuating load.

- 5. The emission source of claim 4, wherein the sufficient power is less than 100 watts.
- 6. The emission source of claim 1, wherein the solid state power source includes an oscillator coupled to a solid state power amplifier.
- 7. An atomic emission detector comprising the emission source of claim 1 and a spectrographic detector disposed to sense atomic emissions from a gas within the resonant cavity.
  - 8. The detector of claim 7 wherein:

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the resonant cavity has a tube disposed along an axis;

the gas enters the tube from one end of the tube, another end of the tube being an open end; and

the spectrographic detector is disposed to sense atomic emissions emitted from the open end.

- 9. The detector of claim 7, further including a cable coupled between the solid state power source and the resonant cavity.
  - 10. The detector of claim 7, wherein:
    the resonant cavity includes a tube disposed through the resonant cavity; and
    the tube comprises one of a fused silica tube and a sapphire tube.
  - 11. The detector of claim 7, wherein:

the solid state power source is coupled to the resonant cavity to provide sufficient power to sustain a plasma in the gas within the tube, the sufficient power being less than 300 watts:

the plasma constitutes a fluctuating load on the solid state power source; and the sufficient power is substantially stable with respect to the fluctuating load.

- 12. The detector of claim 11, wherein the sufficient power is less than 100 watts.
- 13. The detector of claim 7, wherein the solid state power source includes an oscillator coupled to a solid state power amplifier.
- 14. A method of sustaining a plasma comprising steps of:

  passing a gas through a resonant cavity; and

  exciting the resonant cavity with signal power from a solid state power source
  to sustain the plasma in the gas.

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- 15. The method of claim 14, wherein the step of exciting includes exciting the resonant cavity with signal power that is less than 300 watts.
- 16. The method of claim 14, further comprising a step of sensing a wavelength of radiation emitted from the plasma.
- 17. The method of claim 14, further comprising a step of sensing an intensity of radiation emitted from the plasma.
- 18. A method of using a solid state power source, comprising steps of:

  passing a gas through a resonant cavity; and

  coupling sufficient signal power from an output of the solid state power source
  to sustain a plasma in the gas, the sufficient power being less than 300 watts.
- 19. The method of claim 18, further comprising a step of sensing a wavelength of radiation emitted from the plasma.
- 20. The method of claim 18, further comprising a step of sensing an intensity of radiation emitted from the plasma.